Optical Beam Profiling @ BESSY II: Imaging, interferometry and more





New Beamlines for <u>Bunch-Resolved</u> Optical Beam Diagnostics





New Beamlines for <u>Bunch-Resolved</u> Optical Beam Diagnostics

Necessary Properties:

- Nondestructive *detailed* diagnostics for complex fill patterns
- Robust operation and 24/7 availability \rightarrow dipole beamlines
- Bunch-resolved measurements (BII, B-VSR, BIII) $\rightarrow \Delta t \ll 1$ ns



longitudinal bunch parameters (t): phase* + length + shape lateral bunch parameters (x,y): position* # + size# + shape 2D detection methods (for x, y, t): x vs. t, y vs. t, x vs. y

* measured also by BESSY-II bunch-by-bunch feedback sensors / BPMs

measured also by BESSY-II pinhole monitors

Hardware: Beamlines @ Sector L 12





Hardware: Detectors @ Sector L 12



Fast gated Intensified <u>CCD</u> (ICCD), 4 channels w. MCP amplifiers @ 14 bit Exposure Time: $\approx 400 \text{ ps}$ to 80 s, sequence mode Low Jitter : $\approx 10 \text{ ps rms}$ Multiple-gating Repetition Frequency: 100 kHz (\rightarrow 1.5 MHz) Cont. Data Rate: < 20 stored frames /s /cam



Multiframing ICCD camera

Up to 8 channels Up to 100 billion frames per second Based on 4 Picos or 4 Quik E ICCD camera technology UV enhanced system





G. Schiwietz

CCDs: Prosilica GT1920 by Allied Vision

Sensor: Sony ICX674 @ 14 bit, (Magnif. ≈ 0.9)Pixel Size:4.54 μ m × 4.54 μ m, 2.8 MpxlExposure Time:10 μ s to 26 sFrame Rate:< 41 stored frames /s</td>

Fast Synchro-Scan Streak Camera:C10910-05by Hamamatsu (total time resolution = 0.6 ps rms)CMOS-Sensor:16 bit, Image Magnification ≈ 0.6 (total)Pixel Size:6.5 μ m × 6.5 μ m, 1.4 MpxlRepetition frequency, horizontal scan:1 kHzStreaking Time Range:100 ns to 1 μ s (or above)Frame rate:< 70 stored frames /s</td>





Transverse Beam Size: Interferometry vs. Geometrical Optics

Lateral interferometry



Direct imaging of an isotropic emitter is determined by the Abbe limit or Rayleigh criterion (for a 1D slit)

 $\Delta l_{FWHM} = 0.5 \lambda / sin(\alpha_{1/2}),$ with $\alpha_{1/2} = half$ source-opening angle

For a circular 2D aperture, we have $\Delta l \approx 0.61 \lambda / sin(\alpha_{1/2})$

λ _{mean} / direction	α ^{slit} (mrad)	$lpha_{1/2}^{rad.cone}$ (mrad)	Image Resolution: $\sigma_{\! RMS}$ (μ m)
550 nm / horizontal	±10	±3.55	<mark>45 μm</mark> [84 RAY [#] , 60 meas.*]
550 nm / vertical	±2.80	±3.55	75 μm [135 RAY [#] , 115 meas.*]

* CCD white-light fit to central peak + σ pol. @Dip.1.1 after 16 m # incl. slope errors



Following T. Mitsuhashi, "Beam Profile and Size Measurement by SR Interferometer", Beam measu-rement, Ed. by S.Kurokawa et al., pp. 399, World Scientific 1999:

 $\sigma_{RMS} \gtrsim 0.05 \ \lambda / \alpha$, with sin(α) = d/ ℓ and ℓ as source-to-obstacle distance for visibility V = 0.95

→ Double-slit interferometry may improve the resolution by a factor of 10 to 20, assuming the same source-opening angle and the same wavelength.

Lateral interferometry







Gaussian distribution yields

 $\sigma = \frac{\lambda R}{\pi d} \sqrt{\frac{1}{2} \ln \frac{1}{V}}$

High resolution at small beam sizes requires

- Small λ
- Large photon-emission angles $\alpha_{em} \approx d/R$

Reliable curve fitting (determination of V) requires

- Strong light intensity
- Low **vibration** amplitudes
- Low vibration frequencies
- High quality of focusing
 optics (lenses, bandpass filter, maybe vacuum window)

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Master thesis **M. Koopmans:** Resolution = **11** µm rms @ 400 nm (at old test beamline that was never intended for precision measurements)

successful tests of double-slit method (slit separation, wavelength, rotation angle, polarization, interference pattern), see also

- T. Mitsuhashi in: Beam measurement (ed. by S. Kurokawa et al., pp. 399–427, World Scientific 1999).
- M. Koopmans et al., "Applications of the Interferometric Beam Size Monitor at BESSY II", WEPAK009, IPAC2018 Proc., Vancouver, Canada. (2018), 2103-2106.
- M. Koopmans et al., "Vertical Beam-Size Measurement at the BESSY II
 Storage Ring and Their Resolution
 Limits", WEPGW012, IPAC2019 Proc.
 , Melbourne, Australia (2019), 2491-2494.

Lateral interferometry (NEW)





Lateral interferometry

50.94 mm



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Geometrical Ac	ceptance Angles
Horizontal:	±3.02 mrad
Vertical:	±2.16 mrad
	→ ca. ±3.5 mrad

Sector L12 Dip.1.2



Lateral interferometry w. ICCD









2D Streak-Camera Modes: High Time Resolution ($\ll 1 \ ps \ rms$) and Transverse-Size Information



More is possible: 2D analysis



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- Good imaging properties at beamline
- Wide streak camera aperture (V-slit)
 - ⇒ Additional transverse information







Marten Koopmans, DPG Spring Meeting, Dortmund, 2021

G. Schiwietz et al., "Bunch-resolved diagnostics for a future electron-storage ring", NIM-A990, 164992 (2021)

number)

Vertical π -polarization interference

Measurement at streak camera (t/y mode)
 pi-polarisation @ λ = 700 nm
 plus white-noise excitation (0V ... 5 V)



Imholtz

Zentrum Berlin



Open Problems

- Quality for 2D interferometry and extended re-adjustment time changing slit structures (quality of focussing elements +detoriation +edge-diffraction)
- Absolute lateral interferometry with ICCD





Thank you for your attention !



M. Koopmans et al., "*Applications of the Interferometric Beam Size Monitor at BESSY II*", WEPAK009, IPAC2018 Proc., Vancouver, Canada. (2018), 2103-2106.

G. Schiwietz et al., "Development of the Electron-Beam Diagnostics for the Future BESSY-VSR Storage Ring", J.Phys.:Conf. Series 1067, 072005 (2018).

M. Koopmans et al., "Vertical Beam-Size Measurement at the BESSY II Storage Ring and Their Resolution Limits", WEPGW012, IPAC2019 Proc., Melbourne, Australia (2019), 2491-2494.

G. Schiwietz et al., "Bunch-resolved diagnostics for a future electron-storage ring", NIM-A990, 164992 (2021)